as of March 19

April 16 (Tue.)

Time	Program
9:00 - 9:10	Opening
9:10 - 10:10	**Session1** **Opening Session Day1** ***Keynote*** Presenter: Xin Wu (Xilinx, Inc.) ***Invited Talk*** Presenter: Yasumitsu Orii (NAGASE & CO., LTD.)
10:10 - 10:30	Break
10:30 - 11:50	**Session 2** **Litho & Etching**
11:50 - 13:20	Lunch Break
13:20 - 14:30	**Session 3** **FPD** ***Invited Talk*** Presenter: Kouichi Murakami (FSCE Inc.)
14:30 - 14:50	Break
14:50 - 16:10	**Session 4** **Writing & Metrology** ***Invited Talk*** Presenter: Elmar Platzgummer (IMS Nanofabrication GmbH) ***Invited Talk (EMLC 2018 Best Paper)*** Presenter: Klaus-Dieter Roeth (KLA Corporation)
16:10 - 16:30	Break
16:30 - 18:00	**Session 5** **EUVL I** ***Invited Talk*** Presenter: Jan van Schoot (ASML Netherlands B.V.)

April 17 (Wed.)

Time	Program
9:00 - 10:30	**Session 6** **Opening Session Day2** ***Keynote*** Presenter: Atsuyoshi Koike (Western Digital Corporation) ***Invited Talk*** Presenter: Aki Fujimura (D2S, Inc.) ***Invited Talk*** Presenter: Kazutoshi Wakabayashi (NEC Corporation)
10:30 - 10:50	Break
10:50 - 12:10	**Session 7** **EDA & MDP**
12:10 - 13:40	Lunch Break
13:40 - 14:40	**Session 8** **Special Session (MEMS & PUF)** ***Invited Talk*** Presenter: Masayoshi Esashi (Tohoku University) ***Invited Talk*** Presenter: Takeshi Fujino (Ritsumeikan University)
14:40 - 15:00	Break
15:00 - 16:50	**Session 9** **EUVL II** ***Invited Talk*** Presenter: Moshe Preil (KLA Corporation)
16:50 - 18:20	**Session 10** **Poster Session** **10A: Process & Material** **10B: EUVL Masks** **10C: EDA&MDP** **10D: Mask Overlay** **10E: Fab Management** **10S: Mask/Lithography Related Technologies in Academia**
18:20 - 20:20	**Banquet**

April 18 (Thu.)

Time	Program
9:00 - 10:00	**Session 11** **Opening Session Day3** ***Invited Talk*** Presenter: Seiji Nagahara (Tokyo Electron Ltd.) ***Invited Talk (BACUS 2018 Best Paper)*** Presenter: Vicky Philipsen (imec)
10:00 - 10:20	Break
10:20 - 11:40	**Session 12** **EUVL III**
11:40 - 13:10	Lunch Break
13:10 - 15:00	**Session 13** **NIL** ***Invited Talk*** Presenter: Tatsuhiko Higashiki (Toshiba Memory Corporation)
15:00 - 15:20	Break
15:20 - 16:20	**Session 14** **CD & Defect Control**
16:20 - 16:40	Break
16:40 - 18:20	**Panel Discussion**
18:20 - 18:30	Closing